

STIC Search Report

STIC Database Tracking Number 1985

TO: Patricia Martin Location: RND 8a40

Art Unit: 3700

Thursday, June 16, 2005

Case Serial Number: 10/662948

From: Terry Solomon Location: EIC 3700

RND 8b31

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Search Notes

No current or past litigation found involving US pat. 6527018.

Sources:

Lexis/Nexis Questel-Orbit



Time of Request: June 15, 2005 11:21 AM EDT

Research Information:

Utility, Design and Plant Patents patno=6527018

UNITED STATES PATENT AND TRADEMARK OFFICE GRANTED PATENT

6527018

March 4, 2003

Method and system for optimizing batch process of preparing solution

REISSUE: September 16, 2003 - Reissue Application filed Ex. Gp.: 3751; Re. S.N. 10/662,948 (O.G. March 9, 2004)

APPL-NO: 874357 (09)

FILED-DATE: June 6, 2001

GRANTED-DATE: March 4, 2003

ASSIGNEE-AT-ISSUE: Fuji Photo Film Co., Ltd., Kanagawa, Japan (JP), 03

ASSIGNEE-AFTER-ISSUE: September 24, 2001 - ASSIGNMENT OF ASSIGNORS INTEREST (SEE DOCUMENT FOR DETAILS)., FUJI PHOTO FILM CO., LTD. 210 NAKANUMA, MINAMI-ASHIGARA-SHI KANAGAWA JAPAN, Reel and Frame Number: 12191/0958

LEGAL-REP: Sughrue Mion, PLLC - ##0

Selected file: PLUSPAT PLUSPAT - (c) Questel-Orbit, All Rights Reserved. Comprehensive Worldwide Patents database

** SS 1: Results 1 PRT SS 1 MAX 1 LEGALALL

1 / 1 PLUSPAT - ©QUESTEL-ORBIT - image Patent Number : US2002026963 A1 20020307 [US20020026963] Patent Number 2: US6527018 B2 20030304 [US6527018] (A1) Method and system for optimizing batch process of preparing solution Patent Assignee : (A1) FUJI PHOTO FILM CO LTD (US) Patent Assignee : Fuji Photo Film Company, Ltd., Kanagawa [JP] Patent Assignee 2: (B2) FUJI PHOTO FILM CO LTD (JP) Inventor(s): (A1) KUWABARA SHINICHIRO (JP); YAMAUCHI SHINGO (JP) Application Nbr : US87435701 20010606 [2001US-0874357] Priority Details : JP2000170255 20000607 [2000JP-0170255] JP2000202742 20000704 [2000JP-0202742] Intl Patent Class: (A1) B65B-001/04 B65B-003/04 EPO ECLA Class : B01J-004/02 B01J-019/00B G03C-001/015 G05D-011/13B4 US Patent Class: ORIGINAL (O): 141009000; CROSS-REFERENCE (X): 141104000 141105000 Document Type : Corresponding document Citations : US5308593; US5339875; JP4-95700; JP7-71699; JP7-198100 Patent Abstracts of Japan. 07-071699. Mar. 17, 1995. Patent Abstracts of Japan. 07-198100. Aug. 1, 1995. Patent Abstracts of Japan. 04-095700. Mar. 27, 1992. Publication Stage: (A1) Utility Patent Application published on or after January 2, 2001 Publication Stage 2: (B2) U.S. Patent (with pre-grant pub.) after Jan. 2, 2001 Abstract : Each of the batch processing lines has its exclusive one set material processing line independent from others and is operated according to the special algorithm which changes an amount to be prepared in the batch process in a few batches in the final stage of the downstream process based on a calculated total amount required by the downstream process to complete manufacturing. The method for preparing is capable of easily coping with the change of raw materials or prescriptions for the product without increasing or changing existing pipe lines or chemical liquid stock vessels and almost completely avoiding a waste of material. Update Code : 2002-11

1 / 1 LGST - ©EPO

Patent Number :

US2002026963 A1 20020307 [US20020026963]

US6527018 B2 20030304 [US6527018]

Application Number :

US87435701 20010606 [2001US-0874357]

Action Taken :

20010924 US/AS-A

ASSIGNMENT

OWNER: FUJI PHOTO FILM CO., LTD. 210 NAKANUMA, MINAMI-ASH; EFFECTIVE

DATE: 20010704

ASSIGNMENT OF ASSIGNORS INTEREST; ASSIGNORS: YAMAUCHI, SHINGO; KUWABARA,

SHINICHIRO; REEL/FRAME: 012191/0958

20040309 US/RF-A

REISSUE APPLICATION FILED

EFFECTIVE DATE: 20030916

Update Code :

2004-37

1 / 1 CRXX - @CLAIMS/RRX

Patent Number :

6,527,018 A 20030304 [US6527018]

Patent Assignee :

Fuji Photo Film Co Ltd JP

Actions :

20030916 REISSUE REQUESTED ISSUE DATE OF O.G.: 20040309 REISSUE REQUEST NUMBER: 10/662948

EXAMINATION GROUP RESPONSIBLE FOR REISSUEPROCESS: 3751

Reissue Patent Number:

Session finished: 15 JUN 2005 Time 18:28:48 QUESTEL.ORBIT thanks you. Hope to hear from you again soon.